ABSTRACT

An optical device inspection system and method employing a narrow aperture on a magnifying objective lens in order to reduce the circle of confusion and increase the depth of field. The smaller aperture resulting in an increase in depth of field allows for simultaneous focus for all portions of objects being inspected. An arc lamp with an elliptical reflector in combination with a condenser lens focuses a more intense beam of light through the objective lens, thereby providing sufficient brightness without sacrificing any depth of field.